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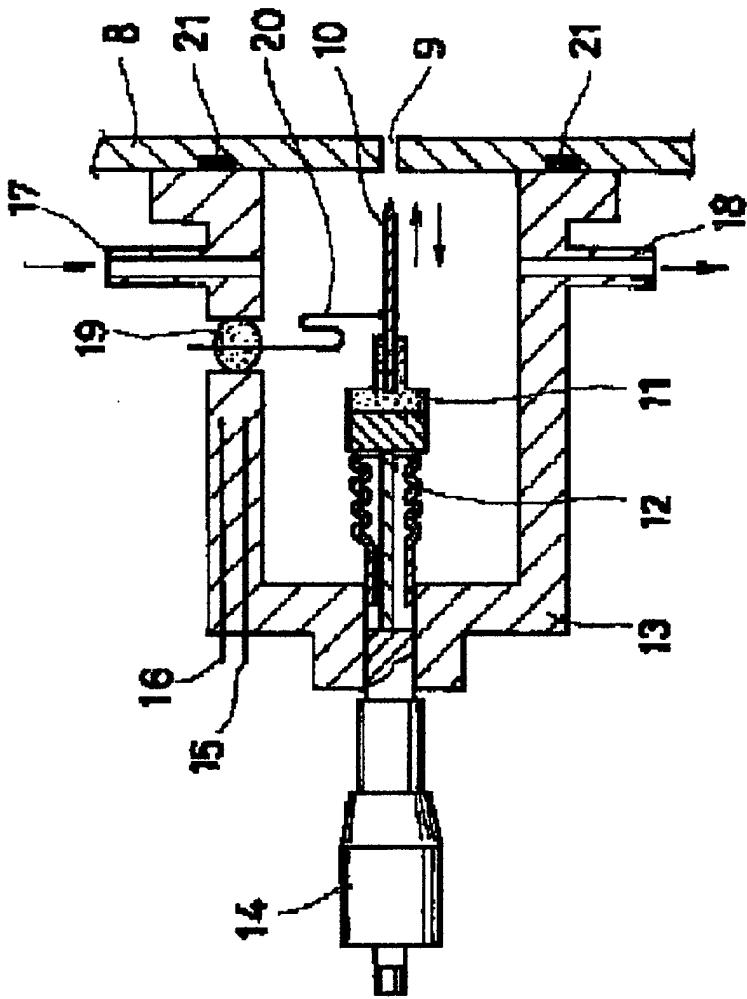
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(54) ION SOURCE FOR
ATMOSPHERIC
PRESSURE IONIZATION
MASS SPECTROMETER
AND ITS DISCHARGE
NEEDLE POSITIONING
DEVICE

(57) Abstract:



PURPOSE: To perform the movement adjustment of the discharge needle of the ion source of an atmospheric pressure ionization mass spectrometer with discharge completed.

CONSTITUTION: This ion source of an atmospheric pressure ionization mass spectrometer is provided with a discharge needle 10 performing ionization by discharging to gas which is the object for mass spectrometry. In a main body 13, in which the casing of the ion source is formed; the discharge needle 10 is joined to the tip of a micrometer 14, fixed to the main body 13, via an insulating insulator 11, and the tip part of the micrometer 14 is covered by a bellows 12 for keeping airtightness. The electrification to the discharge needle 10 is made through the side wall of the main body 13 and the movement of the discharge needle 10 is made by operating the rotation control of the micrometer 14.